

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the applications:

Listing of Claims:

Claim 1 (currently amended). A semiconductor processing system, comprising: a chamber adapted to process a wafer, the chamber having an opening to facilitate access to the interior of the chamber; a lid coupled to the chamber opening, the lid having an open position and a closed position; an actuator coupled to the lid to move the lid between the closed position and the open position; and a self-centering floating pivot coupled to the lid and the actuator to align the lid with the opening when the lid closes.

Claim 2 (previously presented). The system of claim 1, further comprising a fixed pivot coupled to the lid and the actuator.

Claim 3 (previously presented). The system of claim 2, further comprising a guide link coupled to the fixed pivot.

Claim 4 (previously presented). The system of claim 1, further comprising a load link coupled to the floating pivot.

Claim 5 (previously presented). The system of claim 1, further comprising a guide shaft rotatably coupled to the load link.

Claim 6 (previously presented). The system of claim 1, further comprising a drive pivot positioned at one end of the load link.

Claim 7 (previously presented). The system of claim 6, further comprising a rod extending from the actuator coupled to the drive pivot to move the lid.

Claim 8 (previously presented). The system of claim 1, further comprising a support bracket coupled to the actuator and the chamber body.

Claim 9 (previously presented). The system of claim 1, wherein the actuator is air actuated or hydraulically actuated.

Claim 10 (previously presented). The system of claim 1, wherein the actuator is motorized.

Claim 11-23. Cancelled

Claim 24 (currently amended). A semiconductor processing system, comprising: a chamber adapted to process a wafer, the chamber having an opening to facilitate access to the interior of the chamber; and a lid coupled to the chamber opening, the lid having an open position and a closed position, the open and closed positions being moved horizontally translationally in a substantially parallel manner relative to the opening; and an actuator coupled to the lid to move the lid between the closed position and the open position.

Claim 25 (currently amended). The system of claim 24, further comprising a self-centering floating pivot to automatically align the lid to the body of the chamber.

Claim 26 (previously presented). The system of claim 25, wherein the pivot further comprises: a load link having first and second portions; a bearing positioned between the first and second portions of the bearing; and a self-centering spring coupled to the perimeter of the bearing.

Claim 27 (New) A semiconductor processing system, comprising;

a chamber adapted to process a wafer, the chamber having an opening to facilitate access to the interior of the chamber;

a lid coupled to the chamber opening, the lid having an opened position and a closed position;

an actuator coupled to the lid to move the lid between closed position and the opened position; and

a floating pivot coupled to the lid and the actuator to align the lid with the opening when the lid closes;

wherein the actuator is motorized.

Claim 28 (New) A semiconductor processing system, comprising;

a chamber adapted to process a wafer, the chamber having an opening to facilitate access to the interior of the chamber; and

a lid coupled to the chamber opening, the lid having an open position and a closed position, the opened and the closed positions being moved horizontally in a substantially parallel manner relative to the opening; and

a actuator coupled to the lid to move the lid between the closed position and the opened position;

a floating pivot to automatically align the lid to the body of the chamber;

wherein the pivot further comprises:

a load link having first and second portions;

a bearing positioned between the first and second portions of the bearing; and

self-centering spring coupled to the perimeter of the bearing.